

Supporting Information

Dual-control of incubation effect for efficient fabrication in fused silica

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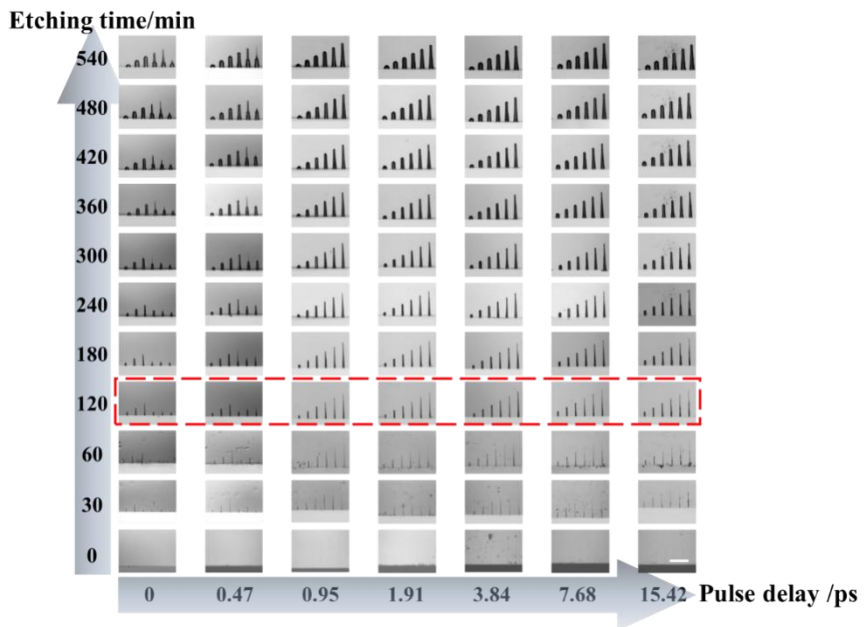


Figure S1. The morphological evolution of gradient height micro-cones with different pulse delays over etching time.
(scale bar: 400 μ m)

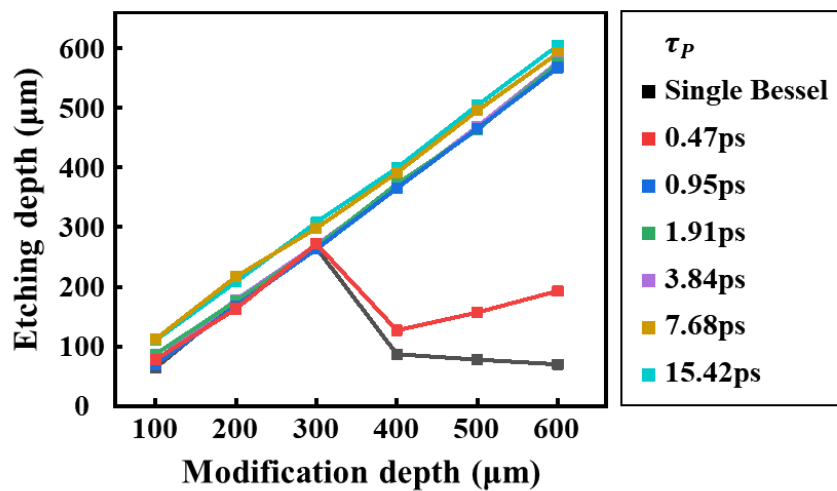


Figure S2. Statistical curves between etching depths and modification depths of gradient height micro-cones with different pulse delays while etching 120 min. (corresponding to the red dashed box in Figure S1)

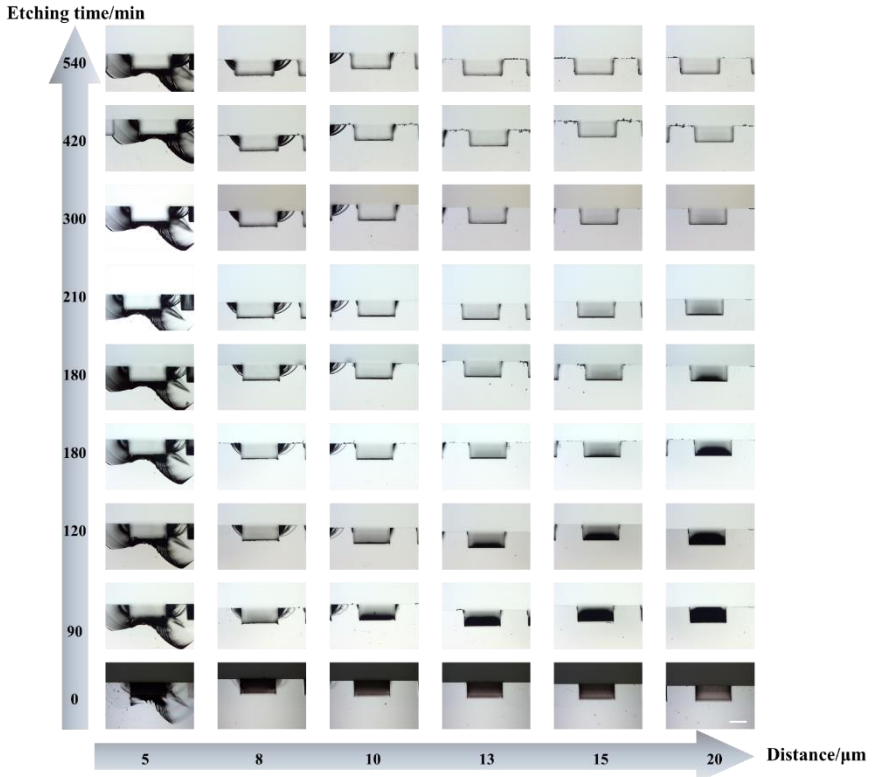


Figure S3. Morphological evolution of 2D grooves with different pulse distance over etching time. (scale bar: 500 μm)

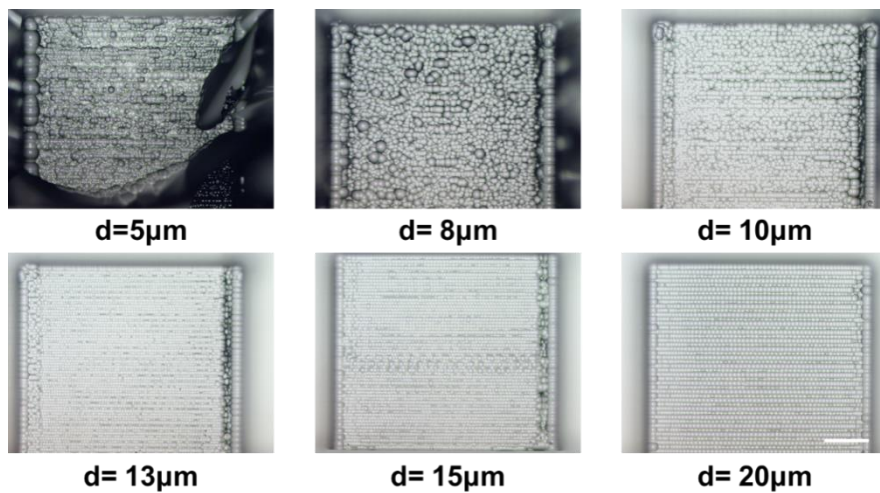


Figure S4. The bottom morphologies of 2D grooves with different pulse distance while etching 480 min. (scale bar: 200 μ m)

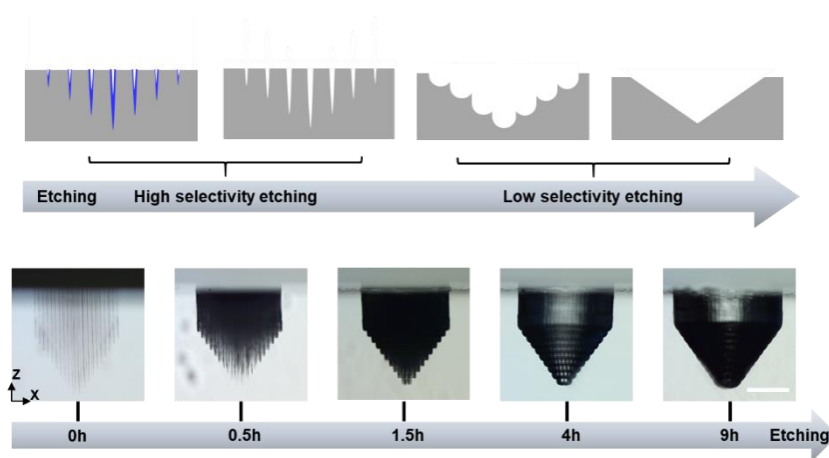


Figure S5. The schematic and OTM images of millimetre scale micro-cone structure morphology evolution with etching time. (scale bar: 200 μ m)